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PATENT
5480-00200/OP99140-US

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Kim

Serial No. 09/287,602

Filed: April 7, 1999

For: GAS SCRUBBER FOR TREATING
THE GAS GENERATED DURING
THE SEMICONDUCTOR
MANUFACTURING PROCESS

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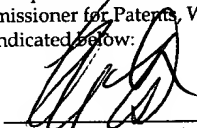
Group Art Unit: 1764

Examiner: Varcoe, F.

Atty. Dkt. No. 5480-00200

I hereby certify that this correspondence is being deposited
with the U.S. Postal Service with sufficient postage as First
Class Mail in an envelope addressed to: **Box: Non-Fee
Amendment**, Commissioner for Patents, Washington, D.C.
20231, on the date indicated below:

June 22, 2001
Date


Kevin L. Daffer

AMENDMENT; RESPONSE TO OFFICE ACTION DATED MARCH 22, 2001

Box: Non-Fee Amendment
Commissioner for Patents
Washington, D.C. 20231

Dear Sir/ Madam:

This paper is submitted in response to the Office Action dated March 22, 2001 to further
highlight reasons why the application is in condition for allowance.

Please amend the case as follows:

In the Claims:

Please replace claim 7 with the amended claim below. A "marked-up" version of each
amendment is included in **Attachment A**.

RECEIVED
JUN 28 2001
TC 1700 MAIL ROOM